



MEMC 98-4650 (2293)
PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Wilson, et al.

Serial No. 09/608,302

Filed June 30, 2000

For A METHOD AND APPARATUS FOR FORMING A SILICON WAFER WITH A
DENUDED ZONE

October 3, 2000

TO THE COMMISSIONER OF PATENTS AND TRADEMARKS,

SIR:

INFORMATION DISCLOSURE STATEMENT

* In accordance with 37 C.F.R. 1.97 and 1.98 and MPEP 609, and in compliance with the
* duty of disclosure set forth in 37 C.F.R. 1.56, applicants enclose a copy of the references listed
on the attached PTO Form 1449 (modified) for consideration by the Patent and Trademark Office
in the above-entitled application and to be made of record herein.


Please note that applicants make no representation as to the accuracy or completeness of
the translations submitted herewith.

NON-ENGLISH LANGUAGE INFORMATION:

Applicants have not obtained English translations of Reference Nos. 31 and 35-38. The
relevance of these references as understood by applicants is set forth in the English language
abstracts submitted herewith.

The Commissioner is hereby authorized to charge any fees incurred regarding this
Information Disclosure Statement to Account No. 19-1345 if an Office action was issued prior to
the date of mailing of this Statement.

Respectfully submitted,

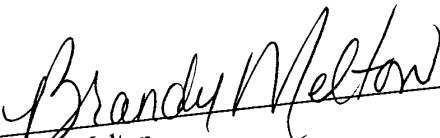

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CERTIFICATE OF MAILING

I certify that this Letter to the Patent and Trademark Office and attached PTO Form 1449 is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on this 3rd day of October, 2000.



Brandy Melton

KFJ/RAS/blm
*Enclosure/Attachment